8030 FULLY AUTOMATIC 12" TWIN



ADT 8030 Dicing system has two facing spindles that can simultaneously dice wafers at high throughput. ADT 8030 is a high accuracy system that can dice product up to 12" in diameter or 12" × 12" product, at high performances and low cost of operation.

FEATURES & BENEFITS

Flexibility - Supports Hub and Hubless blades up to 3" O.D.

Spindles of 1.8 kW or 2.2 kW high power

Bridge type frame supporting efficient wafer processing

Intuitive operation interface using a large 19" touch screen monitor

Fast & simple blade change with a locking spindle shaft

SECS / GEM platform ready

Specifications		8030						
Workpiece Size		Ø 8", Ø 12" or 12" × 12" Square						
Spindle		Two facing 1.8 kW or 2.2 kW shaft lock spindles, max. 60,000 rpm						
Blade Size		2" - 3"						
Y1 / Y2 Axis, Control Resolution Cumulative Accuracy Indexing Accuracy		Linear encoder for each Y axis						
		0.1 μm 1.5 μm 1.0 μm						
							Cutting range	350 mm
						X Axis		Air Slide
Z1 / Z2 Axis, Resolution		0.2 μm						
	Repeatability	① 1.0 μm						
	Max. stroke	50 mm (for 2.188" blade OD)						
θ Axis,	Repeatability	4 arc-sec						
	Stroke	380°						
Cleaning S	Station	Full rinse and dry cycle						
Spinning speed		100-3,000 rpm						
	Cleaning Method	Atomized cleaning capabilities						
Utilities,	Electrical	200-240 VAC, 50/60 Hz, single phase						
Dimensions (W × D × H) mm Weight		1,145 × 1,687 × 1,830						
		1,500 kg						

Note: Specifications are subject to change without notice.

FULLY AUTOMATIC 8" TWIN



ADT 8020 Dicing system has two facing spindles that can simultaneously dice wafers at high throughput. ADT 8020 is a high accuracy system that can dice product up to 8" in diameter, at high performances and low cost of operation.

FEATURES & BENEFITS

Flexibility - Supports Hub and Hubless blades up to 3" O.D. Spindles of 1.8 kW or 2.2 kW high power

Intuitive operation interface using a large 19" touch screen monitor

Fast & simple blade change with a locking spindle shaft

SECS / GEM platform ready

Specifications		8020		
Workpiece Size		Ø 8″		
Spindle		Two facing 1.8 kW or 2.2 kW shaft lock spindles, max. 60,000 rpm		
Blade Size		2" - 3"		
Y1 / Y2 Axis, Control		Linear encoder for each Y axis		
	Resolution	0.1 μm		
	Cumulative Accuracy	1.5 μm		
	Indexing Accuracy	1.0 µm		
	Cutting range	210mm		
X Axis		Air Slide		
Z1 / Z2 Axis, Resolution		0.2 μm		
	Repeatability	1.0 µm		
	Max. stroke	30 mm (for 2.188" blade OD)		
θ Axis,	Repeatability	4 arc-sec		
	Stroke	380°		
Cleaning Station		Full rinse and dry cycle		
	Spinning speed	100-3,000 rpm		
	Cleaning Method	Atomized cleaning capabilities		
Utilities,	Electrical	200-240 VAC, 50/60 Hz, single phase		
Dimensions (W × D × H) mm		1,015 × 1,460 × 1,820		
	Weight	1,300 kg		

Note: Specifications are subject to change without notice.

7900/20/30 **AUTOMATIC TWIN**



ADT 7900 series has two facing spindles that can simultaneously dice wafers or packages at high throughput. ADT 7900 series is a high accuracy system that can dice product at high performances and low cost of operation.

Basic machine models:

7900 Duo support Ø 8" 7920 Duo up to 10" × 10" 7930 Duo up to 12" × 10" or Ø 12"

FEATURES & BENEFITS

Fast & Simple Blade Change

SECS/GEM platform ready

Full access to any area of the system for easy maintenance

Air bearing feed axis (X)

Fast automatic alignment and cut positioning for increased throughput

Specifi	cations	7900 Duo	7920 Duo	7930 Duo		
Workpiec	e Size	Ø 8" 10" × 10" 12" × 10" or Ø 1		12" × 10" or Ø 12"		
Spindle		Two facing 1.8 kW or	Two facing 1.8 kW or 2.2 kW shaft lock spindles, max. 60,000 rpm			
Blade Size	·	2" - 3"				
Y1 / Y2 Ax	is, Control	Line	ear encoder for each Y	axis 💍 🔘		
	Resolution		0.1 µm			
	Cumulative Accuracy		1.5 µm			
	Indexing Accuracy		1.0 µm	1		
X Axis		Air Slide				
Z1 / Z2 Axis, Resolution		0.2 µm				
	Repeatability		1.0 µm			
	Stroke	30	mm (for 2.188" blade	OD)		
θ Axis,	Repeatability		4 arc-sec			
	Stroke		350°			
Utilities,	Electrical	200-24	0 VAC, 50/60 Hz, single	phase D		
Dimension	ns (W × D × H) mm	875 × 975 × 1450				
	Weight		900 kg			

Note: Specifications are subject to change without notice.



DICING EQUIPMENT



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7 1 XX 2" AND 4" SPINDLE DICING SYSTEM



The 7120 / 7130 families of 2" and 4" spindle dicing systems deliver a high level of affordability and flexibility to support your needs.

FEATURES & BENEFITS

Support 2"-3" and 4"-5" blade O.D. with large 'Z' stroke

'X' axis air bearing for smooth motion and super cut quality

Automation with high resolution optics

Multi panel dicing

Custom process solution

Fast & simple blade change with a locking spindle shaft (for 2" spindle)

				///	
Specifications	7122	7124	7132	7134	
Workpiece Size	Ø	8"	Ø 12" or 300mm × 300mm W/O frame		
Spindle	60K rpm / 1.8 kW	50K rpm / 1.8 kW 30K rpm / 2.5 kW		30K rpm / 2.5 kW	
Blade Size	2" - 3"	4" - 5"	2" - 3"	4" - 5"	
Y Axis, Control	Linear encoder for each Y axis				
Resolution	0.1 μm				
Cumulative Accuracy	1.5 µm				
Indexing Accuracy	1.0 µm				
X Axis	Air Slide				
Z Axis, Resolution	0.2 μm				
Repeatability	1.0 μm				
θ Axis, Repeatability	4 arc-sec				
Stroke	350°				
Utilities, Electrical	200-240 VAC, 50/60 Hz, single phase				
Dimensions (W × D × H) mm	965 × 1300 × 1600				
Weight	900 kg				

Note: Specifications are subject to change without notice.

71MD 2" DICING SYSTEM FOR MEDICAL



The 71MD dicing system is designed for demanding and tight applications such as PZT. The system is equipped with Height on parts measuring system and it can be provided with large Z clearance. It can also be supplied with a balancing tool to minimize spindle vibration, typical for Ultra-Sound sensors applications.

FEATURES & BENEFITS

Multi Panel handling

Custom Jigs

Geometric Model Finder (GMF)

Large Z clearance

Low-vibration spindle

High resolution water flow coolant

Z Linear encoder

Height Measuring Tool (HMT)

Specifications	71MD			
Workpiece Size	Ø 8"			
Spindle	60K rpm / 1.8 kW 2" - 3"			
Blade Size				
Features	Z Linear encoder			
	Z Clearance			
//////////////////////////////////////	Height on parts			
	GMF - Geometrical Model Finder			
Y Axis, Control	Linear encoder for each Y axis 0.1 µm 1.5 µm			
Resolution				
Cumulative Accuracy				
Indexing Accuracy	1.0 µm			
X Axis	Air Slide			
Z Axis , Resolution	0.2 μm			
Repeatability	1.0 µm			
θ Axis, Repeatability	4 arc-sec			
Stroke	350°			
Utilities, Electrical	200-240 VAC, 50/60 Hz, single phase			
Dimensions (W × D × H) mm	965 × 1300 × 1600			

Note: Specifications are subject to change without notice.

71TS 2" TILTED SPINDLE



The Tilting Spindle dicing system is designed to meet the needs of Optoelectronic component manufacturers by providing both perpendicular cuts and 8° angular cuts needed to suppress backreflection in fiber optic components.

The system offers quick changeover from perpendicular (0°) to any angle up to 15°.

TYPICAL APPLICATIONS

Silicon, Silica-on Silicon Polymers on Si

InP GaAs Fiber Wave Guides LiNbO3

Fused Silica

Specifications	71TS				
Workpiece Size	Ø 8"				
Spindle	60K rpm / 1.8 kW				
Blade Size	2" - 3"				
Features	Two preset angles: - First angle at 0°				
	- Second angle at 0°C-15°				
	- Fine angle adjust capability				
Y Axis, Control	Linear encoder for each Y axis				
Resolution	0.1 μm 1.5 μm				
Cumulative Accuracy					
Indexing Accuracy	1.0 μm				
X Axis	Air Slide				
Z Axis , Resolution	0.2 μm				
Repeatability	1.0 μm				
θ Axis, Repeatability	4 arc-sec				
Stroke	350°				
Utilities, Electrical	200-240 VAC, 50/60 Hz, single phase				
Dimensions (W × D × H) mm	965 × 1300 × 1600				
Weight	900 kg				

Note: Specifications are subject to change without notice.

72XX FULLY AUTOMATIC DICING SYSTEM



The 7200 system offers a wide range of advanced automation and process monitoring option to meet the throughput and quality requirements of your most challenging dicing applications: silicon, glass on silicon, glass, BGA & QFN packages, LTCC, ceramic, PCB and other hard material applications.

FEATURES & BENEFITS

Efficient wafer handling system

Continuous digital magnifications vision system

Blade wear prediction algorithm reduces height measurement time and increases UPH

Atomized wafer cleaning technology for superior process results

Specifications	7222	7223	7224	7200-300 2"	7200-300 4"		
Workpiece Size		Ø 8"			Ø 12" or 253mm × 243mm		
Spindle	60K rpm	60K rpm / 1.8 kW		60K rpm / 1.8 kW	30K rpm / 2.5 kW		
Blade Size	2"	2" - 3"		2" - 3"	4" - 5"		
Y Axis, Control		Linear encoder for each Y axis					
Resolution		0.1 μm					
Cumulative Accura	су		1.5 µm				
Indexing Accuracy	y		1.0 µm				
X Axis			Air Slide				
Z Axis , Resolution		0.2 μm					
Repeatability							
θ Axis , Repeatability		4 arc-sec					
Stroke		350°					
Cleaning Station		Full	rinse and dry o	ycle			
Spinning speed			100-2,000 rpm				
Cleaning Method		Atomiz	ed cleaning cap	abilities			
Utilities, Electrical		200-240 VAC, 50/60 Hz, single phase					
Dimensions (W × D × H) m	ım 9	65 × 1460 × 170	00	1100 × 17	85 × 1700		
Weight		1,200 kg		1,35	0 kg		

Note: Specifications are subject to change without notice.

^{*} Special 7100 XLA available with 2" and 4" spindle covering 24" × 18"